

Robust liquid metal collector mirror for EUV and soft X-ray plasma sources

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New
Lambda




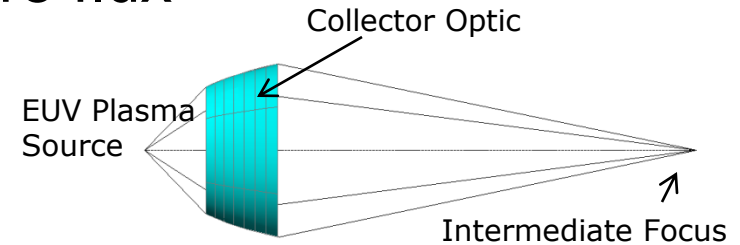
Overview

- Motivation
- First Prototypes (Cone + Flat)
- Current Prototypes (Cylinder + Ellipsoid)
- Zemax Modelling
- Focused EUV – First Results
- Lifetime Monitoring
- Planned Work

Motivation

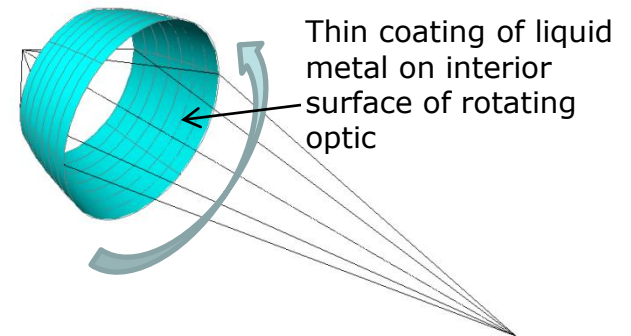
- EUV Sources for Metrology

- Simple collector  $\sim 10^4$ more flux
- Requires atomically flat mirror
- Sn Plasma debris + fast ions
 - Lifetime issues



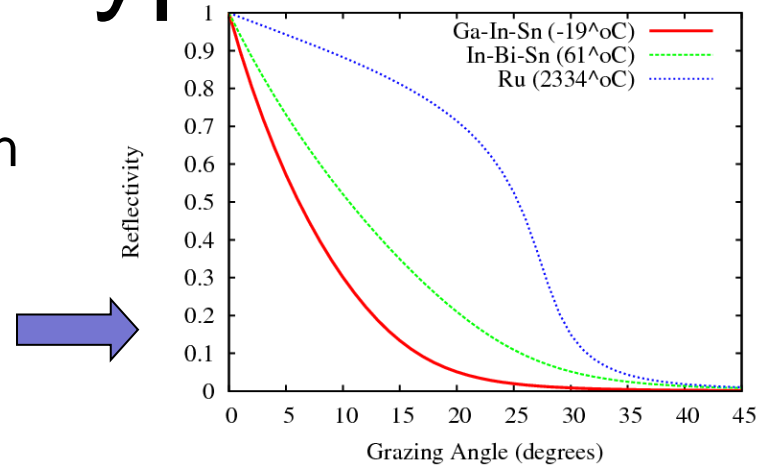
- Liquid metal coated mirror

- Sn based alloy
- Relatively long lifetime
- No debris mitigation



First Prototypes

- Established coating mechanism on rotating optic
 - GaInSn alloy ; Melting pt -19°C
 - Theoretical R v θ at 13.5 nm (92eV)
(from http://henke.lbl.gov/optical_constants/mirror2.html)

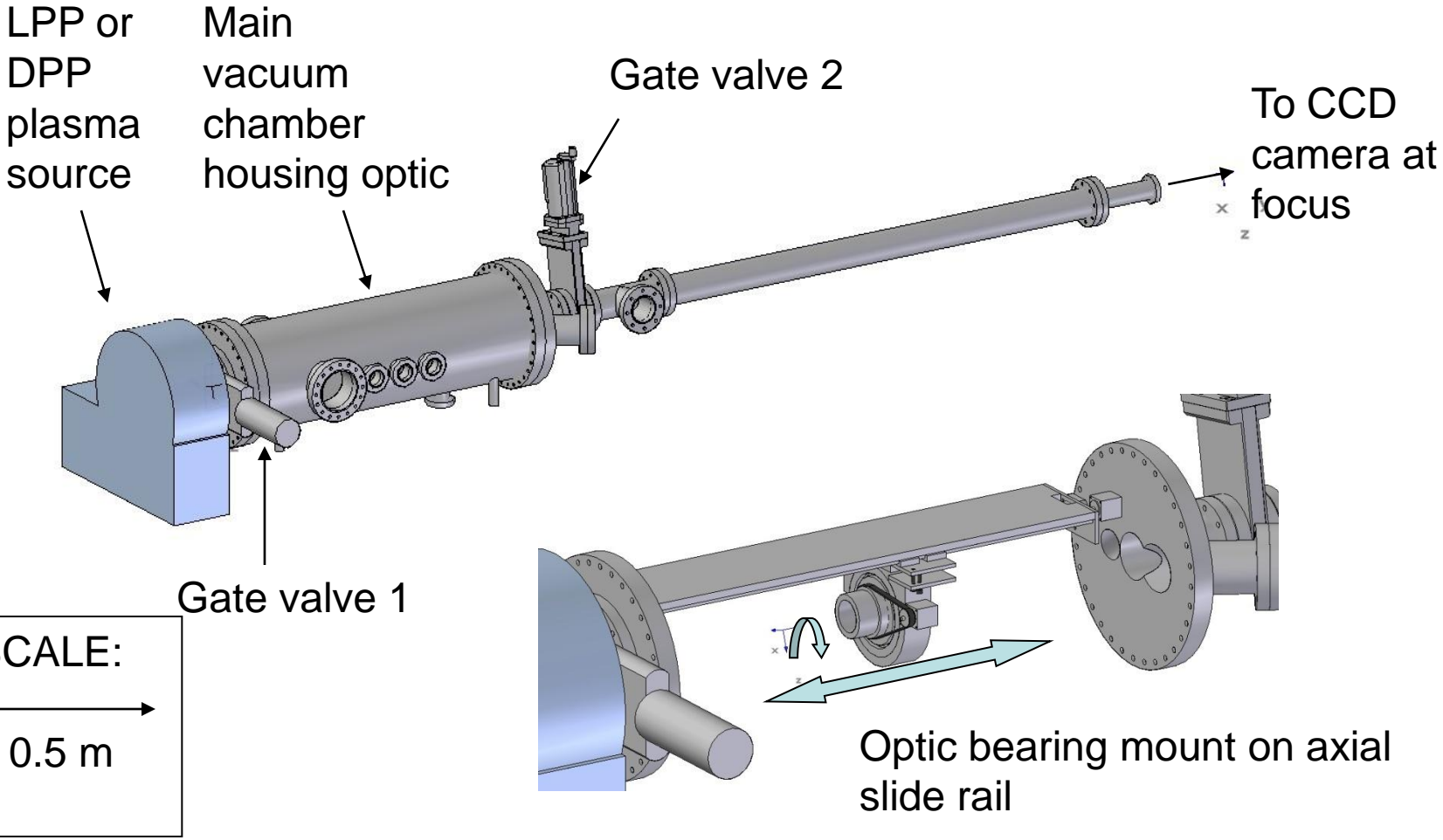


Cone: Dia: 100mm



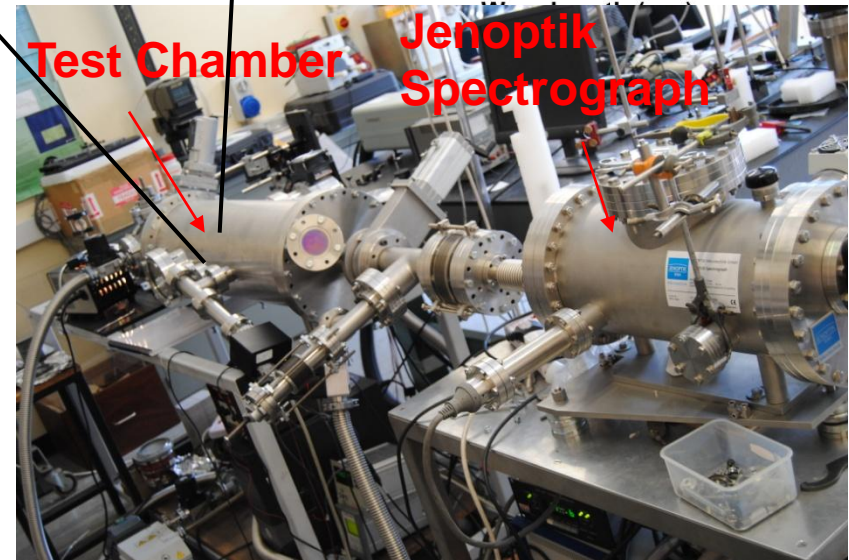
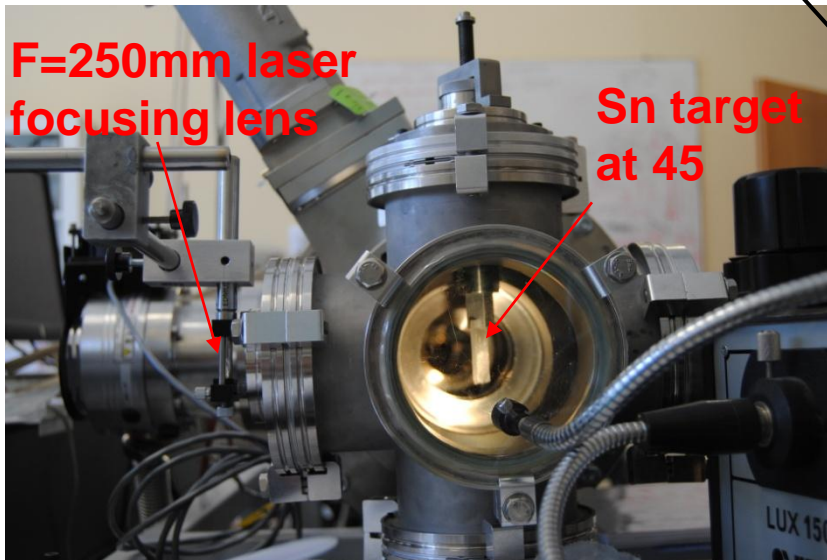
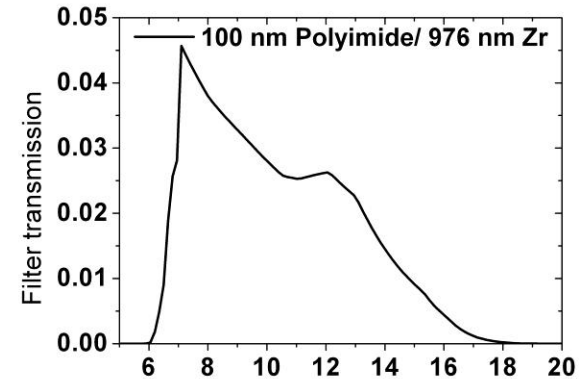
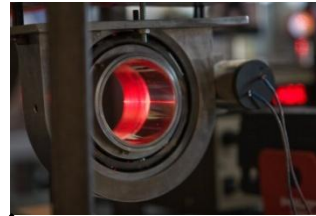
Plane: Dia: 100mm

Focusing EUV: Exp. Design



EUV Testing: Initial Setup

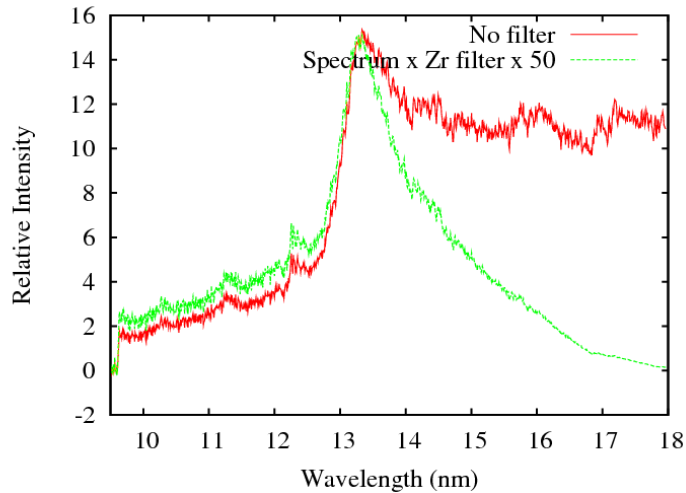
- ❑ Sn LPP source
- ❑ Optic: Cylinder shell 80 mm x 55 mm (LxDia)
- ❑ 100 nm Poly/976 nm Zr EUV filter
- ❑ CCD camera: Princeton Instruments PI-SX, 1024x1024, 13 μm pixels.



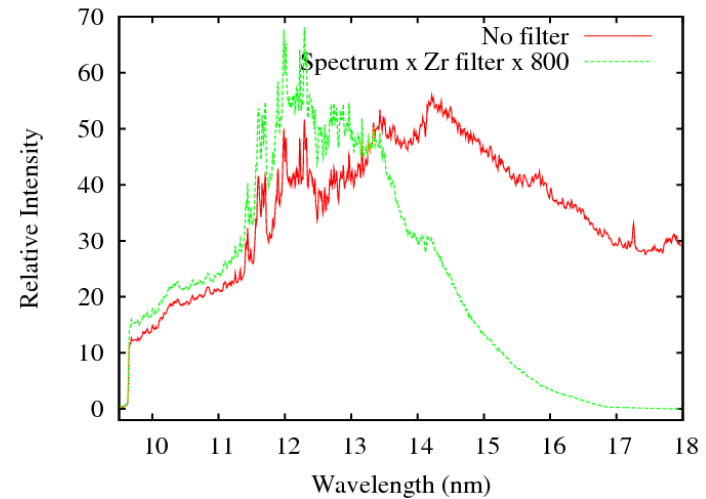
Source Spectra

- Jenoptik Espec grazing incidence spectrograph

Pure Sn Spectrum
 $\Phi \sim 3 \times 10^{10} \text{ Wcm}^{-2}$

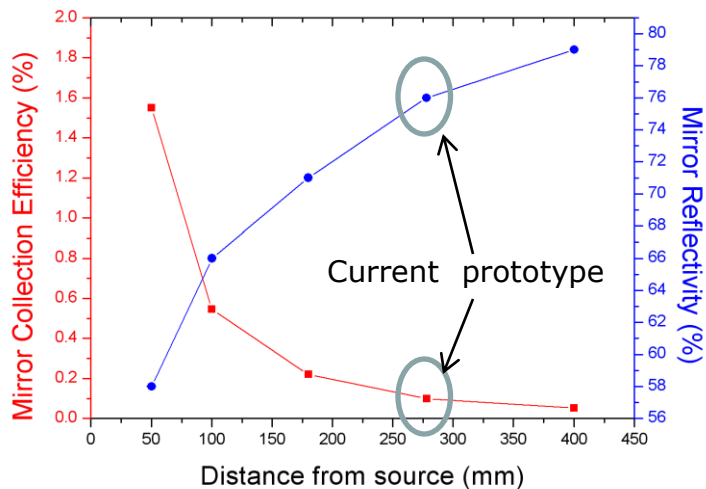


Liquid target Spectrum (GaInSn)
 $\Phi \sim 3 \times 10^{11} \text{ Wcm}^{-2}$



Zemax Modelling

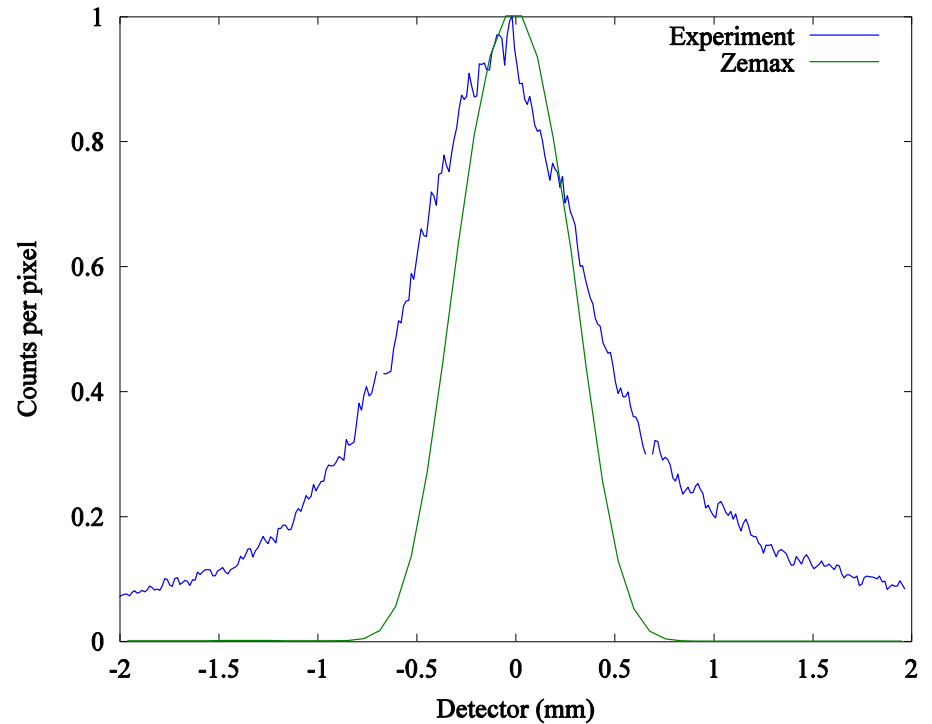
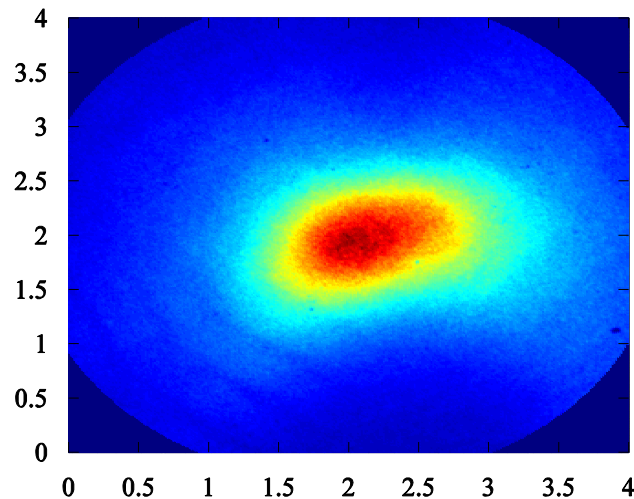
- Cylinder + Ellipsoid performance modelled
- Optimization of Ellipsoid for typical DPP source



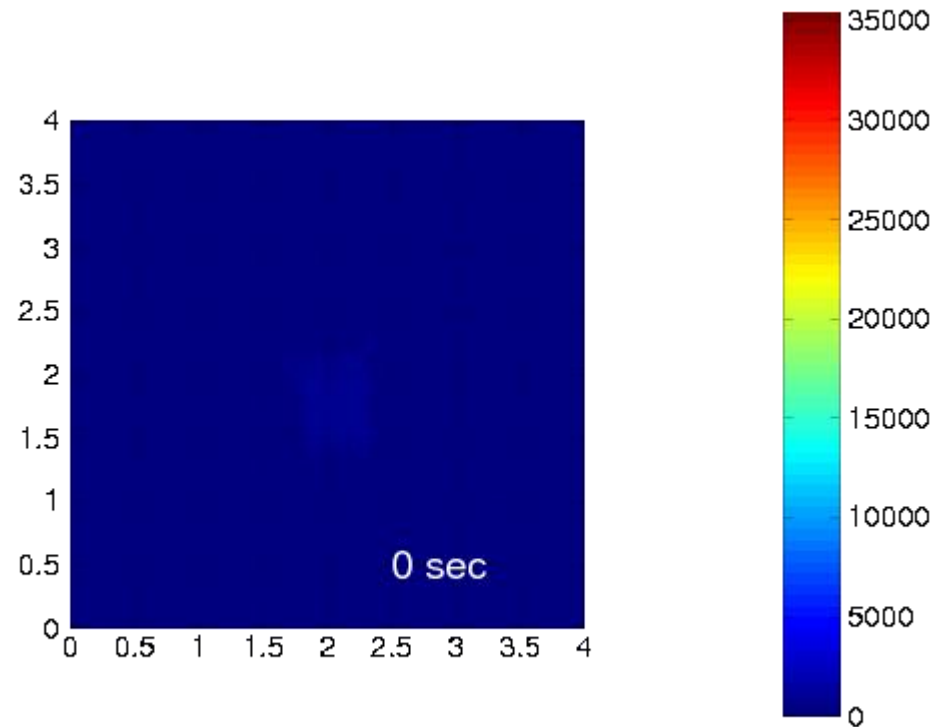
	Present Collector	Optimized Collector I	Optimized Collector II
In-band Power at source (W)	11.2	11.2	11.2
Source radius or FWHM (mm)	0.345	0.345	0.345
Source to mirror distance (mm)	278	200	25
Magnification	13.6	3.2	2.6
Average Reflectivity (%)	78	67	18
Power Density at Image (mW/mm ²)	0.4	14.4	151.9
Power Density No Collector (mW/mm ²)	0.0002	0.0024	0.029

Focused EUV – First Results

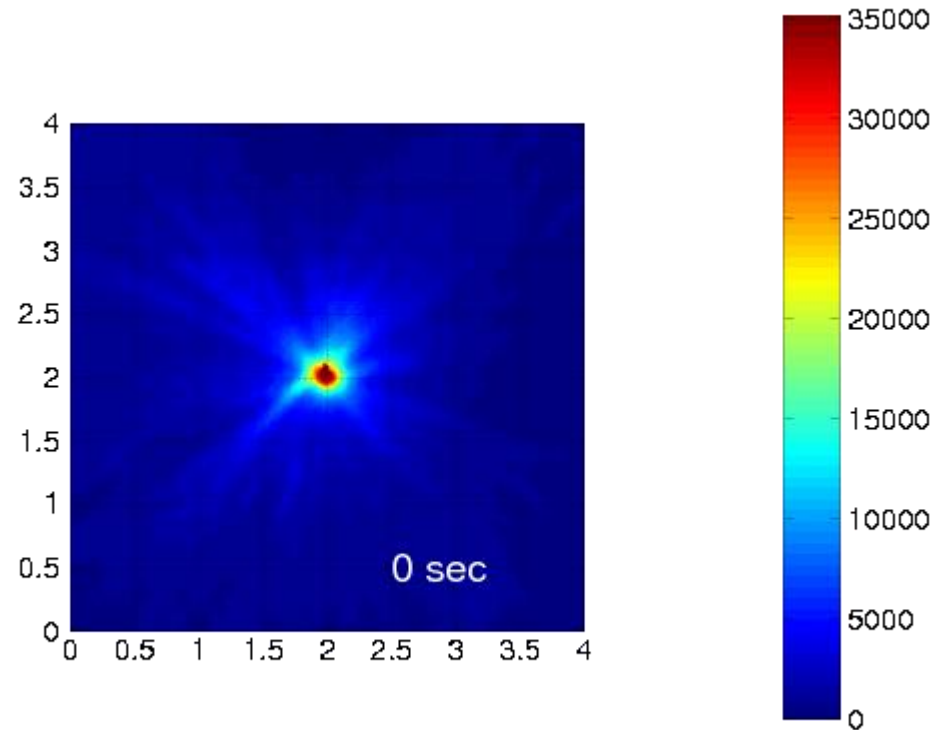
- Ellipsoid Section



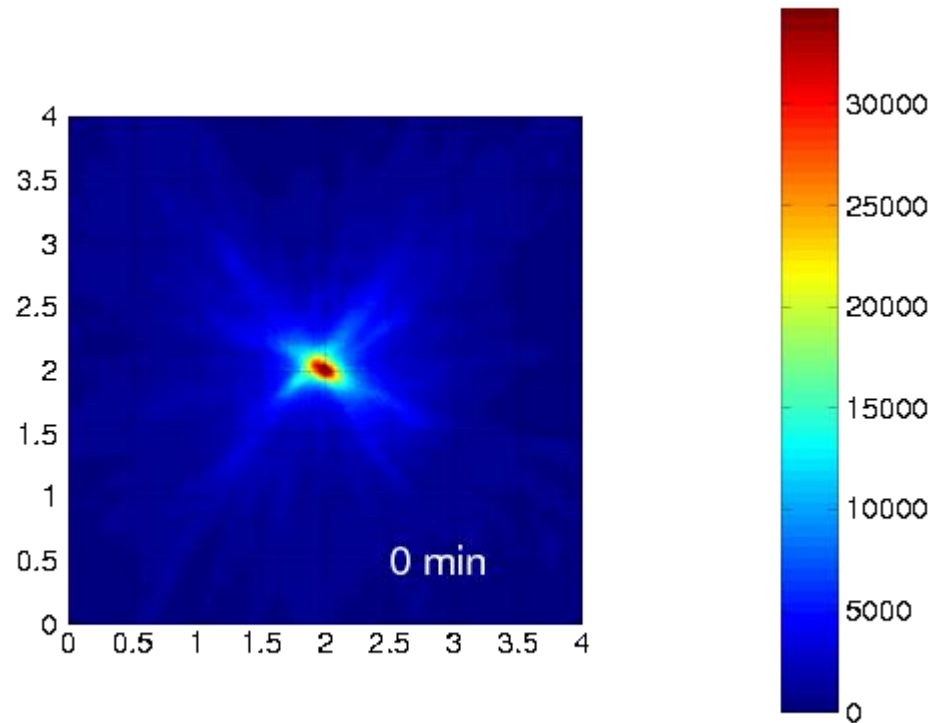
Mirror Start-up



Mirror Running



Mirror Stopping



Lifetime Testing

- 20 W LPP Plasma
- Plasma to mirror distance = 200 mm

# Pulses (x1000)	# EUV Photons collected	Image fwhm (μm)
0	3.08×10^6	290
200	2.78×10^6	299
400	3.11×10^6	292
600	3.01×10^6	302
800	3.05×10^6	286

Ongoing Work

- Characterise EUV Source
- Optically characterise ellipsoid figure error
- Zemax – Application specific optimum mirror shapes
- Long term operation in front of commercial DPP or LPP source

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